

INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

Docket Number (Optional)

FIS920020093US2

Application Number

Applicant(s)

Allen et al.

Filing Date

Group Art Unit

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JF		5,246,532	09-21-93	Ishida			
		6,251,792	06-26-01	Collins et al.			
		6,068,784	05-30-00	Collins et al.			
		5,888,414	03-30-99	Collins et al.			
		5,707,486	01-13-98	Collins			
		5,556,501	09-17-96	Collins et al.			
		2002/0004309 A1	01-10-02	Collins et al.			

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

JF		"Wafer Arcing - Etch's Secret Hurdle" Shawming Ma, Semiconductor International Vol. 25, No. 12, pg. 50

EXAMINER

DATE CONSIDERED

1-12-2006

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.